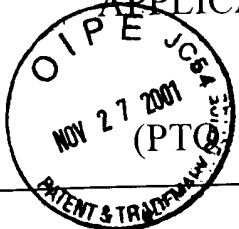


INFORMATION DISCLOSURE CITATION IN AN APPLICATION


 ATTY. DOCKET NO.
50212-270

 SERIAL NO.
09/942,101

 APPLICANT
Yoshi NISHIBAYASHI, et al.

 FILING DATE
August 30, 2001

 GROUP
4765-2879

U.S. PATENT DOCUMENTS

EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
<i>AN</i>	6,184,611	2/6/2001	Saito et al.			


FOREIGN PATENT DOCUMENTS

EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	Yes/No	
						Yes	No

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

	Hiroshi SHIOMI et al., "High Rate Reactive Etching of Diamond and Fabrication of Porous Diamond for Field-Emission Cathode", NEW DIAMOND, Vol. 13, No. 4, pp. 28-29.
<i>AN</i>	K. Okano et al., "Mold growth of polycrystalline pyramidal-shape diamond for field emitters", DIAMOND AND RELATED MATERIALS 5, 1996, pp. 19-24. <i>no month</i>
<i>AN</i>	W.P. Kang et al., "Micropatterned polycrystalline diamond field emitter vacuum diode arrays", American Vacuum Society, 1996, pp. 2068-2071. <i>no month</i>
EXAMINER	DATE CONSIDERED
<i>Joseph Williams</i> <i>AN</i>	<i>5/29/03</i>

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.

INFORMATION DISCLOSURE CITATION IN AN APPLICATION  (PTO-1449)				ATTY. DOCKET NO. 50212-270		SERIAL NO. 09/942,101	
				APPLICANT Yoshi NISHIBAYASHI, et al.			
				FILING DATE August 30, 2001		GROUP 4765-2879	
U.S. PATENT DOCUMENTS							
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE	
<i>JW</i>	5,916,005	06/29/1999	BAIK et al.			TC 1700	JAN 04 2002
	5,199,918	04/06/1993	KUMAR				
	5,619,093	04/08/1997	GLESENER et al.				
FOREIGN PATENT DOCUMENTS							
EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						Yes	No
<i>JW</i>	10-312735	11/24/1998	Japan (English Abstract only)				
	11-204022	07/30/1999	Japan (English Abstract only)				
	WO 97/15531 A1	12/28/1996	WIPO/OMP PCT				
	WO 98/44529 A1	10/08/1998	WIPO/OMP PCT				
	EP0836217A1	04/15/1998	EPO				
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)							
<i>JW</i>	"Anisotropic etching of a fine column on a single crystal diamond" Nishibayashi et al., <i>Diamond and Related Materials</i> , Elsevier Science Publishers, Amsterdam, NL, Vol. 10, NR. 9-10, pp. 1732-1735, ISSN: 0925-9635						
	7th International Conference on New Diamond Science and Technology, July 23, 2000, Hong Kong, China						
<i>JW</i>	"Diamond tip fabrication by air plasma etching of diamond with an oxide mask" Eun-Song Baik et al., <i>Diamond and Related Materials</i> , No. 8, 1999, pp. 2169-2171, XP002184096 <i>no month</i>						
	"Homoepitaxial growth on fine columns of single crystal diamond for a field emitter" Yoshiaki Nishibayashi et al., <i>Diamond and Related Materials</i> , No. 9, 2000, pp. 290-294, XP002184097 <i>no month</i>						
<i>JW</i>	"Diamond 1999, the 10th European Conference on Diamond, Diamond-Like Materials...", September 12, 1999, Prague						
EXAMINER <i>Joseph Williams</i>				DATE CONSIDERED <i>5/29/03</i>			

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.